

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Satoshi Watanabe  
Serial No.: to be assigned  
Filed: concurrently herewith  
For: *RESIST MATERIAL AND PATTERN FORMING METHOD*

Date: January 18, 2002

Commissioner for Patents  
Washington, DC 20231

**PRELIMINARY AMENDMENT**

Sir:

Prior to the examination of the above application, please amend the above-identified application as follows.

**IN THE SPECIFICATION:**

Please amend the specification as follows:

At page one, following the title " RESIST MATERIAL AND PATTERN FORMING METHOD", please insert

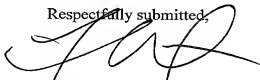
**-- Related Application**

This application claims priority from Japanese Patent Application No. 2001-012947, filed on January 22, 2001, the disclosure of which is incorporated by reference herein in its entirety.--

**REMARKS**

The above amendment is made to claim priority to the identified Japanese patent application.

Respectfully submitted,



F. Michael Sajovec  
Registration No. 31,793

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Page 2 of 2



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PATENT TRADEMARK OFFICE

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Date of Deposit: January 18, 2002

I hereby certify that this correspondence is being deposited with the United States Postal Service "Express Mail Post Office to Addressee" service under 37 CFR 1.10 on the date indicated above and is addressed to:  
BOX PATENT APPLICATION, Commissioner for Patents, Washington, DC 20231.

Monica L. Croom  
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